

LVEM5

Low Voltage Electron Microscope

Nanoscale from
your benchtop





COMPACT BUT POWERFUL

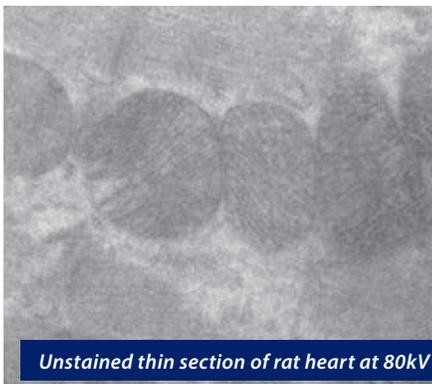
The LVEM5 is designed to excel across a broad range of applications in material sciences, such as nanomaterials, polymers and biomaterials, and in life sciences, such as drug discovery and delivery, pathology and virology. The LVEM5 offers a high throughput benchtop solution with nanometer resolutions.

Benchtop Design: Imaging where you need it most

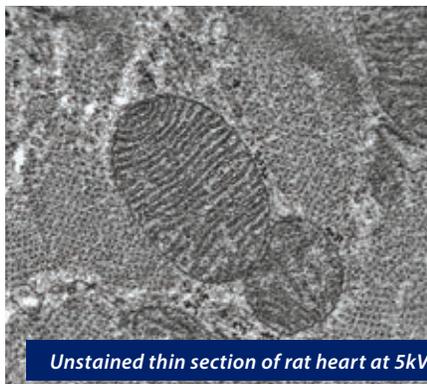
The LVEM5 has an architecture that departs from traditional models. The benchtop design alone is a significant architecture and footprint departure from classical TEM design. The LVEM5 is approximately 90 % smaller than classical electron microscopes. This means that the LVEM5 can be installed in a lab, on a desktop or benchtop; almost anywhere electron imaging is needed. It features a small footprint and is easy to service. There is no need for a dark room or cooling water.

High Contrast

The LVEM5 is a unique investigative tool which combines transmission (TEM, STEM) and surface scanning (SEM) observation modes. High contrast on light elements comes from the 5 kV accelerating voltage, which is substantially lower than in conventional TEM (typically 80–200 kV). This results in increased electron scattering and enhanced contrast on biological, organic and light materials.



Unstained thin section of rat heart at 80kV



Unstained thin section of rat heart at 5kV

COMPONENTS

Field Emission Gun: High brightness and high contrast

The uniquely-designed Schottky type field emission gun employed by the LVEM5 has very high brightness and spatial coherency with a lifetime of several thousand hours. The high brightness and small virtual source of the electron gun enables high-resolution transmission and scanning modes.

Permanent magnet lenses: Cooling not required

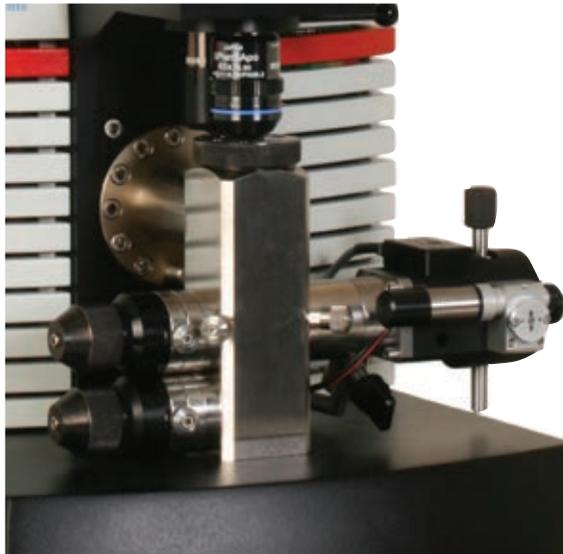
In another industry first, the LVEM5 is designed to operate without any cooling. With conventional electron microscopes active cooling is required to remove considerable heat generated by electric current circulating in the electromagnetic lenses. Uniquely designed permanent magnet lenses used in the LVEM5 remove any need for cooling of its components.

Ion Getter Pumping: Clean vacuum, clean column, clean images

Ion pumps are inherently dry, vibration-free and achieve very high vacuum levels. By making use of specially designed Ion Getter Pumps, the LVEM5 avoids all contamination in the sample space, resulting in stable imaging conditions and absence of artifacts.

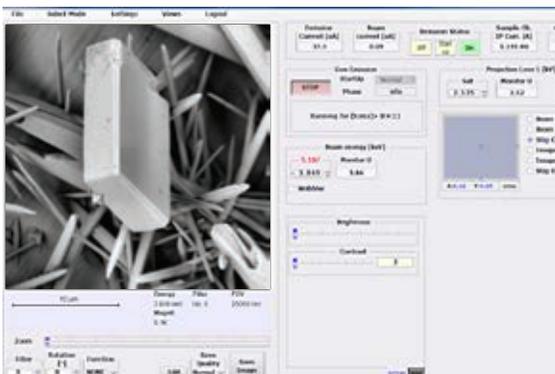
Transmission Electron Microscopy: Inline, two stage optics platform

Electron optics provide the initial stages of magnification. Electrons travel upwards through objective and projectors. They continue towards the YAG scintillator screen for formation of the initial image. High spatial resolution on the YAG screen enables using high light-optical magnification in a unique two stage magnification system.



Light optics that are stable and reliable further magnify the initial image on the YAG screen. There is highly efficient light transport from the fluorescent screen into the light optics.

Digital Imaging in TEM mode is by means of a Peltier cooled CCD camera mounted on the top of the LVEM5. Image capture is via QImaging Retiga 4000R, a high sensitivity digital camera with 2048x2048 pixel progressive scan interline CCD. The image capture software is designed for acquisition, documentation, and analysis of high performance image data. Various image processing procedures, such as averaging, live FFT and automatic contrast adjustment are available.

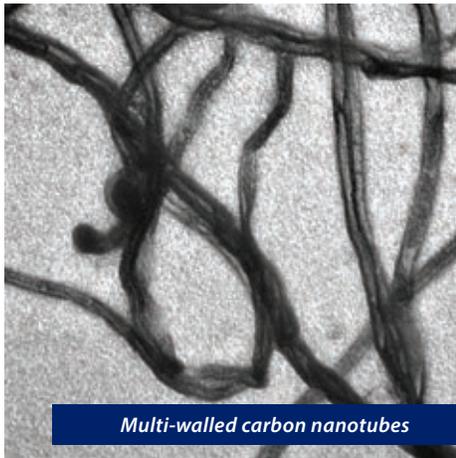


LVEM5 for Material Sciences

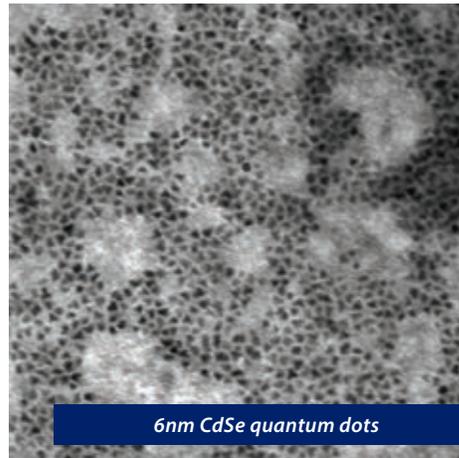
Materials science is a complex field of study applying the different properties of matter to various areas of science and engineering, and has been propelled to the forefront because of its significance in nanotechnology. One of the most important tools available to scientists to investigate the structure of materials at atomic or molecular scales is the electron microscope.

The LVEM5 electron microscope assists researchers in the field of materials science by providing high resolution and rapid imaging of their samples. The LVEM5 shifts the cost-benefit balance by providing nanometer level resolution across 3 imaging modes: TEM (Diffraction included), SEM and STEM. The LVEM5 system combines all these functions in an easy-to-operate tabletop electron microscope, and helps keep time-to-results and efforts-to-results at minimal levels.

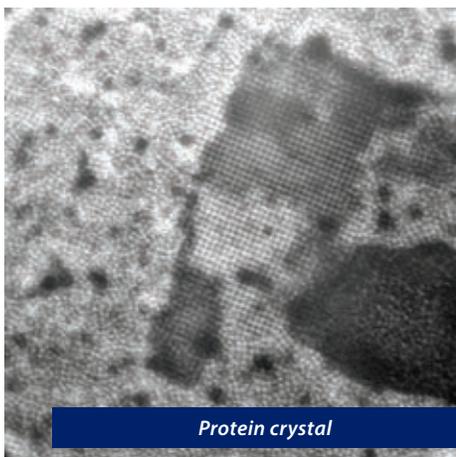
Whether you're studying polymers, nanostructures, composites or blends, the LVEM5 represents a uniquely powerful tool for your research.



Multi-walled carbon nanotubes



6nm CdSe quantum dots



Protein crystal



Silicon wafer

LVEM5 for Life Sciences

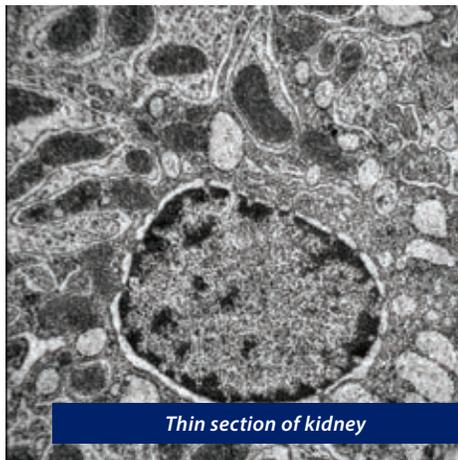
Samples in the life sciences are normally a major challenge to image in an electron microscope due to inherent low contrast provided by their molecular composition. This is not the case when using the LVEM5 in life sciences applications. Issues with sample contrast are eliminated entirely.

Low energy electrons, as found in the LVEM5, interact much more strongly with the sample than high energy electrons of classical TEM. Electrons in the LVEM5 are strongly scattered by organic materials resulting in exceptional differentiation of features.

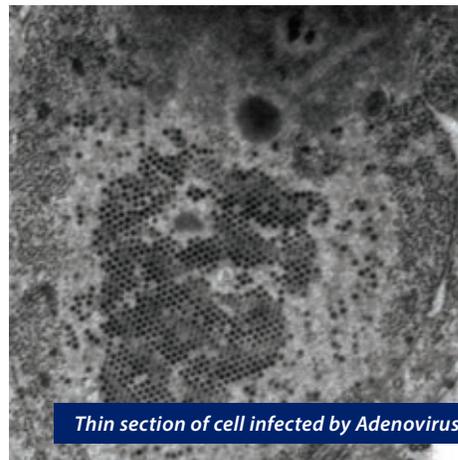
The low accelerating voltage allows the system to provide high contrast results with no addition of contrast-enhancing staining procedures.

The LVEM5 still allows for staining as an option, yet high contrast results are acquired from samples in their inherent, natural state.

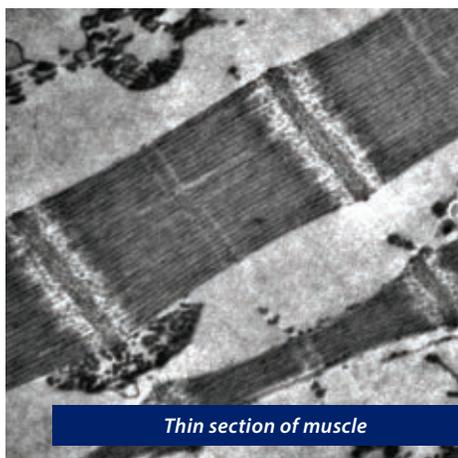
For life scientists, getting high contrast images of unstained samples is something that conventional TEM simply cannot do. The LVEM5 provides high quality results unmatched anywhere else.



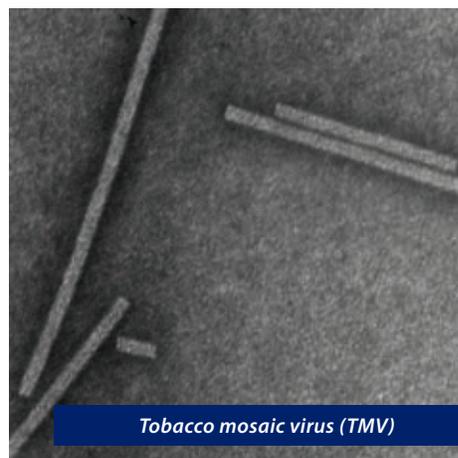
Thin section of kidney



Thin section of cell infected by Adenovirus



Thin section of muscle

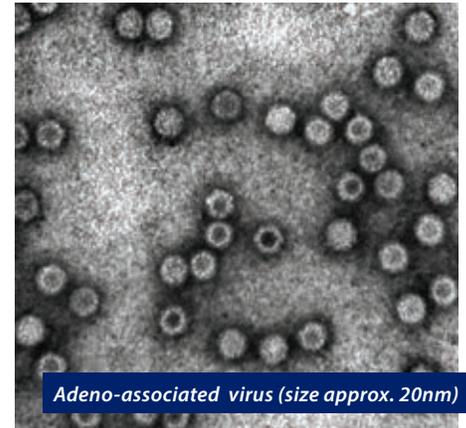


Tobacco mosaic virus (TMV)

TEM BOOST

enhanced imaging module

TEM BOOST is a hardware-based enhancement of TEM imaging mode that provides increased total magnification and higher resolving power in the TEM images. The magnification range is improved to 1,400–700,000 \times . Combined with an improved resolving power of 1.2 nm, this yields a TEM image resolution of 0.2 nm/pixel at maximum magnification. For nanoparticle analysis this means significantly improved size and shape measurements of objects in the 2–10 nm range. For thin sections this means a larger field of view and enhanced image quality throughout the full range of magnifications.



Adeno-associated virus (size approx. 20nm)

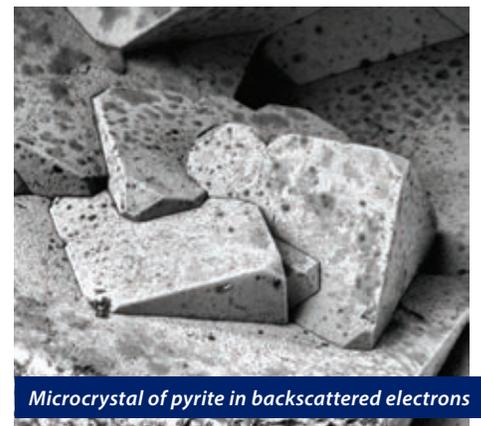
SPECIFICATIONS

| | LVEM5 | LVEM5 with TEM BOOST | Improvement |
|----------------------------|------------------------|------------------------|-----------------------------|
| TEM resolution | 2 nm | 1.2 nm | 40 % more resolving power |
| Magnification range | 2,200–230,000 \times | 1,400–700,000 \times | 200 % more magnifying power |

Scanning Electron Microscopy: Integrated detector for multiple modes

In yet another industry first, a backscattered electron detector has been directly incorporated into an electron optics column that was originally designed for transmission electron microscopy alone, enabling scanning electron microscopy to be performed in parallel.

In SEM mode, the electron beam is focused into a narrow spot, and then scanned repeatedly over the sample. The back-scattered electrons are collected by an annular solid-state detector. Images can be saved at resolutions up to 2048 \times 2048 pixels.



Microcrystal of pyrite in backscattered electrons

SPECIFICATIONS

| OPERATION | | TEM IMAGE CAPTURE | |
|--|-------------------------------|--|-----------------------|
| Nominal accelerating voltage | 5 kV | Camera | Retiga 4000R CCD |
| Specimen size | standard ϕ 3.05 mm grids | Sensor size | 2048×2048 pixels |
| Time for sample exchange | approx. 3 min. | Digitalization | 12 bits |
| IMAGING MODES | | Pixel size | 7.4×7.4 μ m |
| BASIC TEM | | Cooling | Peltier cooling |
| Resolving power | 2.0 nm | SCAN IMAGE CAPTURE | |
| Total magnification | 2,200–230,000× | Monitor | 512×512 pixels |
| TEM BOOST | | Saving image | up to 2048×2048 |
| Resolving power | 1.2 nm | Digitalization | 8 bits |
| Total magnification | 1,400–700,000× | LIGHT OPTICS | |
| ELECTRON DIFFRACTION | | Objective Olympus M 40x | NA* 0.95 |
| Minimum probe size | 100 nm | Objective Olympus M 4x | NA* 0.13 |
| Camera length (binning 1x1) | 2,100 pixels | <i>*numerical aperture</i> | |
| Camera constant (binning 1x1) | 36.3 nm pixels | | |
| STEM | | VACUUM | |
| Resolving power | 2.5 nm | AIRLOCK SYSTEM | |
| Maximum magnification | 250,000× | Diaphragm and turbomolecular pump | 10 ⁻⁵ mbar |
| Maximum field of view | 25×25 μ m | OBJECT SPACE | |
| SEM (BSE DETECTOR) | | Ion getter pump | 10 ⁻⁸ mbar |
| Resolving power | 3 nm | ELECTRON GUN | |
| Maximum magnification | 100,000× | Ion getter pump | 10 ⁻⁹ mbar |
| Maximum field of view | 200×200 μ m | CONSUMPTION | |
| ELECTRON OPTICS | | Control electronics in standby | 20 VA |
| CONDENSER LENS | | Control electronics | 160 VA |
| The smallest illuminated area | 100 nm | Including airlock pumping system | 300 VA |
| Condenser aperture | Φ 50, 30 μ m | Camera | 24 VA |
| OBJECTIVE LENS | | PC and monitor | 450 VA |
| Focal length* | 1.26 mm | <i>No cooling water for the microscope is required</i> | |
| C _s (spherical aberration coefficient) | 0.64 mm | | |
| C _c (chromatic aberration coefficient) | 0.89 mm | WEIGHTS AND DIMENSIONS | |
| α_{theor} (theoretical aperture angle) | 10 ⁻² rad | ELECTRON AND LIGHT OPTICS | |
| Objective aperture | Φ 50, 30 μ m | Weight | 25 kg |
| <i>*calculated for 5 kV</i> | | Dimensions (w/o camera) | 29×45×43 cm |
| PROJECTION LENS | | AIRLOCK PUMPING SYSTEM | |
| BASIC TEM | single lens | Weight | 17 kg |
| TEM BOOST | double lens | Dimensions | 30×30×34 cm |
| ELECTRON GUN | | CONTROL ELECTRONICS | |
| Current density | 0.2 mAsr ⁻¹ | Weight | 19 kg |
| Lifetime | >2,000 hours | Dimensions | 47×27×27 cm |

DISTRIBUTION

The LVEM5 is supported globally by sales and service offices in local markets. Please consult our website for the distributor in your country. You can also contact us directly for any questions you may have or to be referred to your distributor.

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